

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application Serial No. ....09/212,726  
Filing Date ..... December 15, 1998  
Inventor..... Klaus F. Schuegraf  
Assignee .....Micron Technology, Inc.  
Group Art Unit.....2813  
Examiner ..... Blum, David S.  
Attorney's Docket No. ....MI22-1098  
Title: Semiconductor Processing Methods of Chemical Vapor Depositing SiO<sub>2</sub> on a  
Substrate

**RESPONSE TO MAY 10, 2006 OFFICE ACTION**

To: Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

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**AMENDMENTS**

**Introductory Comments**

In reply to the office action dated May 10, 2006, applicant amends and remarks as follows.